Structure and Optical properties of HfO2 nano films grown by PLD for optoelectronic device

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Abstract. The high purity and good transparent conductive nano and micro hafnium oxide (HfO2) films were deposited successfully using the pulsed laser deposition (PLD) method. The optical result shows a high transparency reached to (93) %. The value of the optical band gab of the deposited films at the optimum preparation condition is about 5.3eV, the surface morphology give a uniforms structure with the average roughness of (0.3 nm).